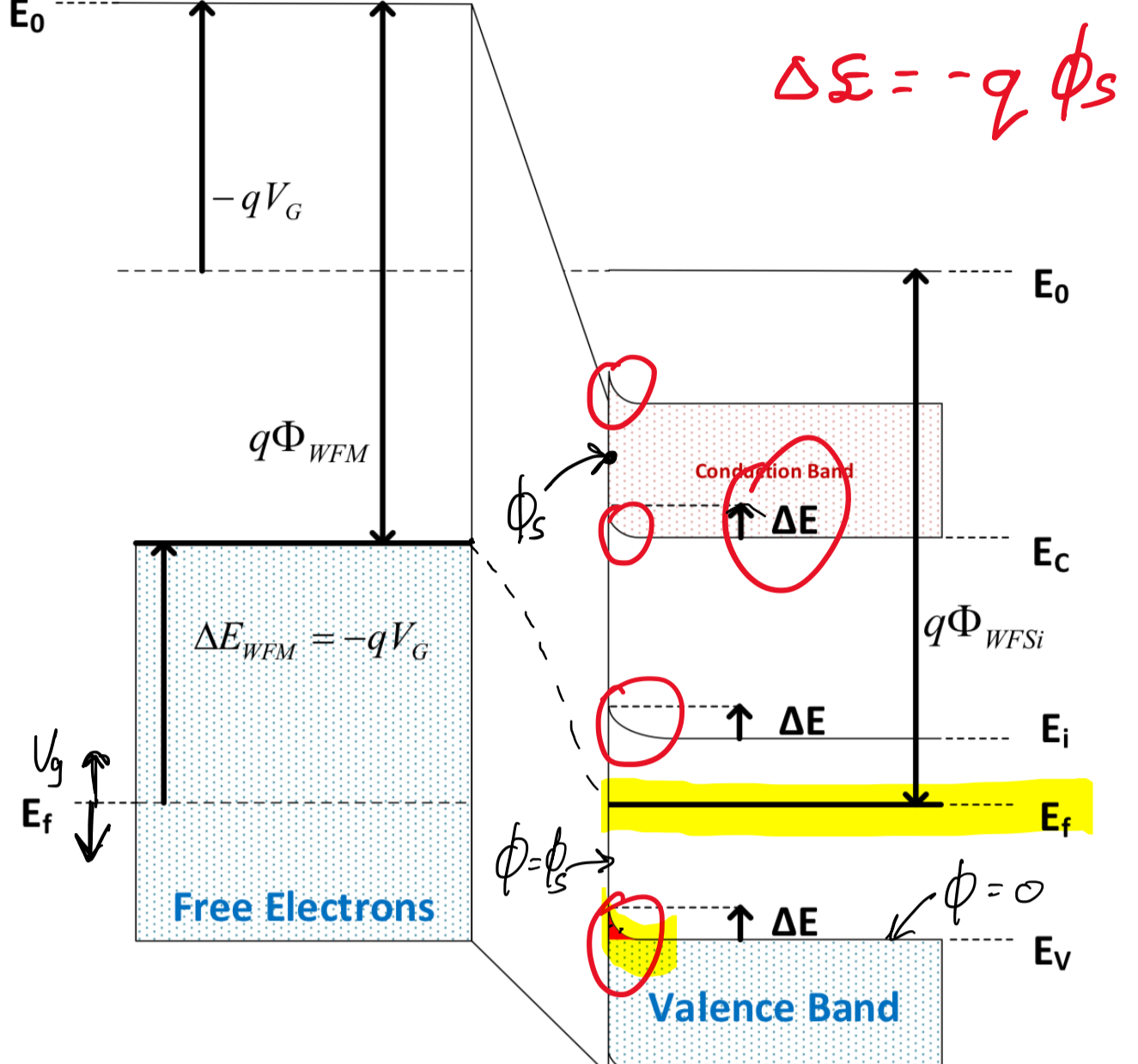


Accumulation Band View

- Set $V_g < 0$
- Results in Metal Fermi-Level shift of $\Delta E_{FM} = -qV_g$
- Causes Si Bands to bend near interface
 - Bends by an amount $-q\phi_s$
 - Where ϕ_s is the potential at the interface
- Si Fermi Level Fixed by Doping
- Bent Valence band closer to E_f
 - Hole conc. Higher
 - Higher accumulation of holes at the interface
- Holes because substrate is p-type
 - More correctly majority charge carriers



Potential $\phi(x)$ & Accumulation Thickness x_{acc}

- Bands tell us to expect more holes @ Interface
 - Due to some unknown potential gradient $\phi(x)$
- Let's calculate how many more holes: Poisson's Equation!

$$\frac{d^2 \phi(x)}{dx^2} = \frac{-\rho(x)}{\epsilon_{Si}} = \frac{-q}{\epsilon_{Si}} [P - N_D - N_A]$$

$P = N_A e^{\frac{-q\phi(x)}{kT}}$

n & $N_D \approx 0$ Since p-type material

$P =$ Thermally Generated & Dopant Introduced Holes

$N_A =$ Fixed Dopant Atoms (Ions)

Poisson's Equation Simplifies:

~~$$\frac{d^2 \phi(x)}{dx^2} = \frac{-q N_A}{\epsilon_{Si}} \left[e^{\frac{-q\phi(x)}{kT}} - 1 \right]$$~~

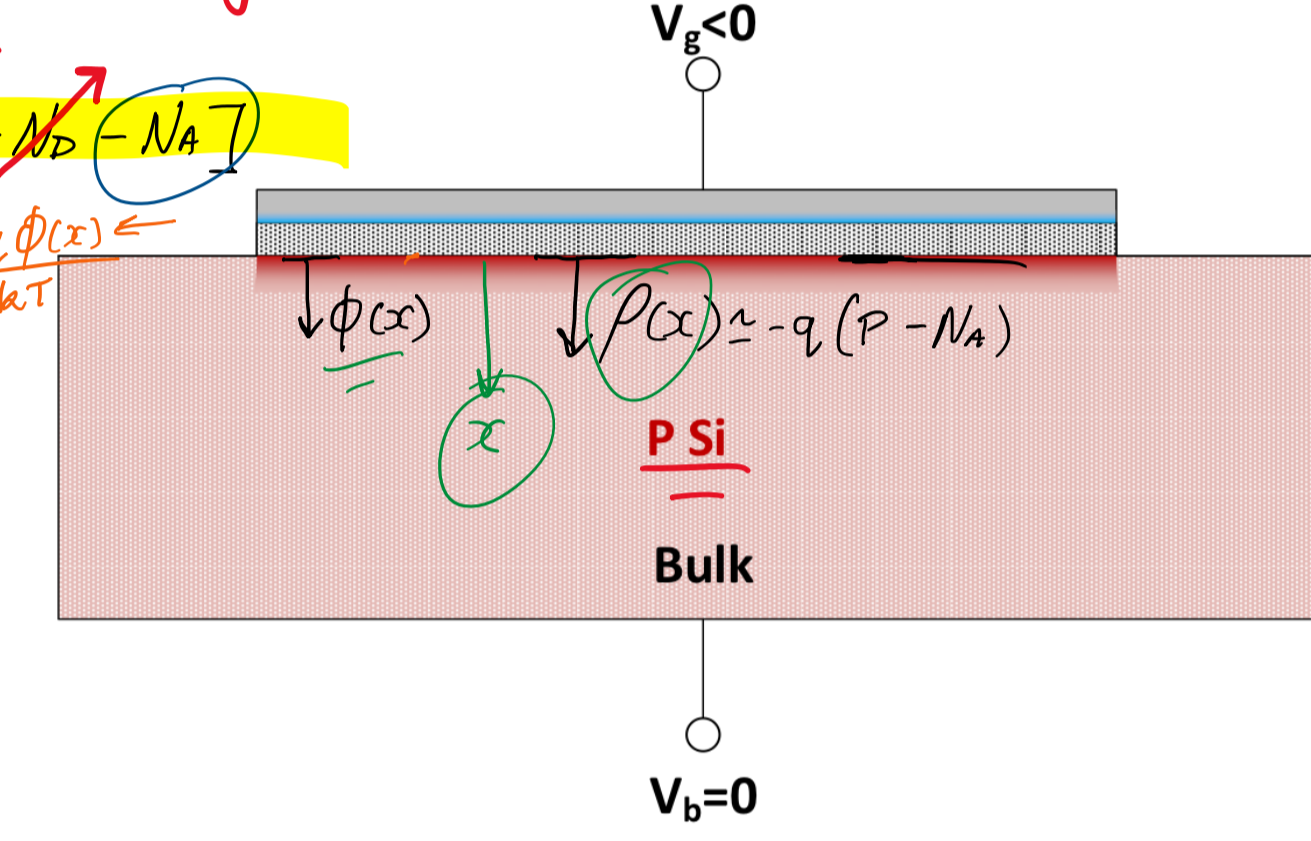
- Poisson would be a pain to solve
- Let someone else solve it and plot it instead
- Almost all the surface potential is dropped over a small distance regardless of surface potential!
- Normalise result to different Doping Concentrations with Debye Length:

$$L_D = \sqrt{\frac{\epsilon_{Si} kT}{q^2 N_A}}$$

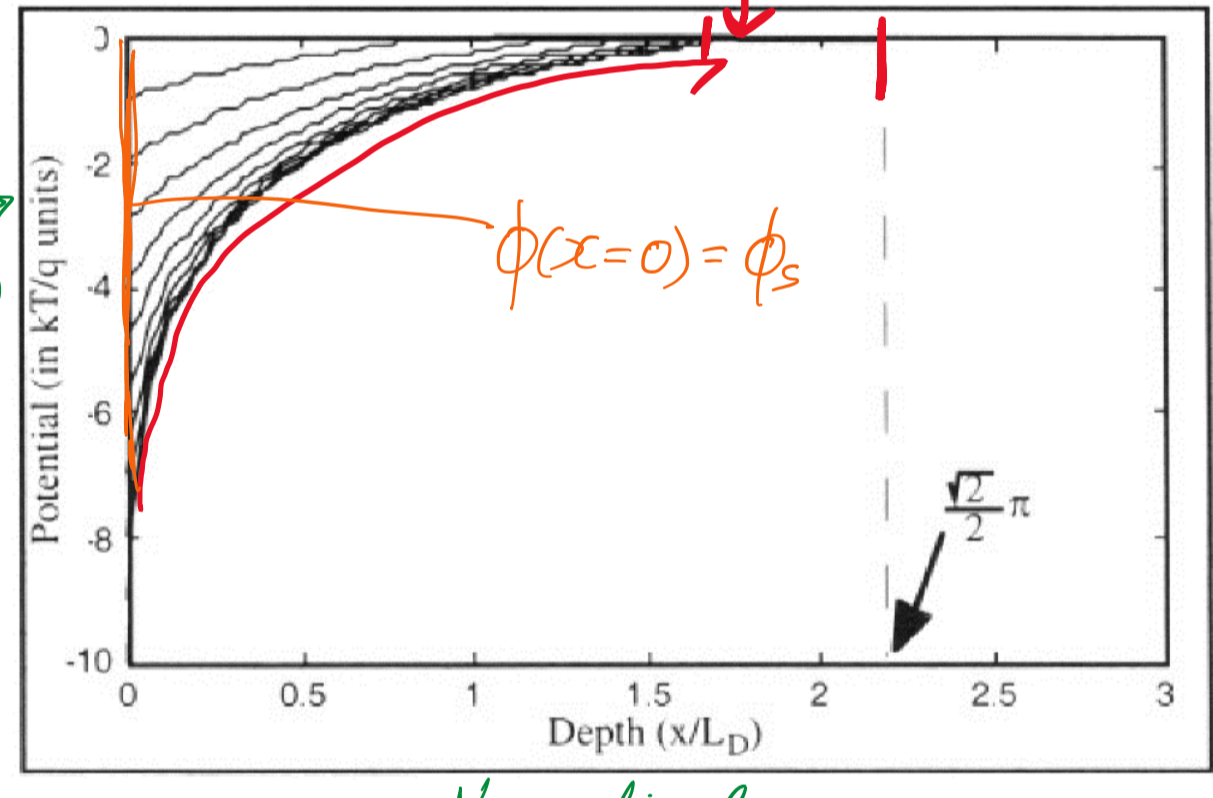
All potential (thus all charge) accumulated within:

$$x < \frac{\pi}{\sqrt{2}} L_D = x_{acc}$$

Usually very thin, a few nm



- If we know $\phi(x)$, we know $\rho(x)$
- Thus accumulation charge!
- But solving Poisson's Eqn requires solving 2nd order differential Eqn



Normalised Depth x/L_D

Accumulation Charge

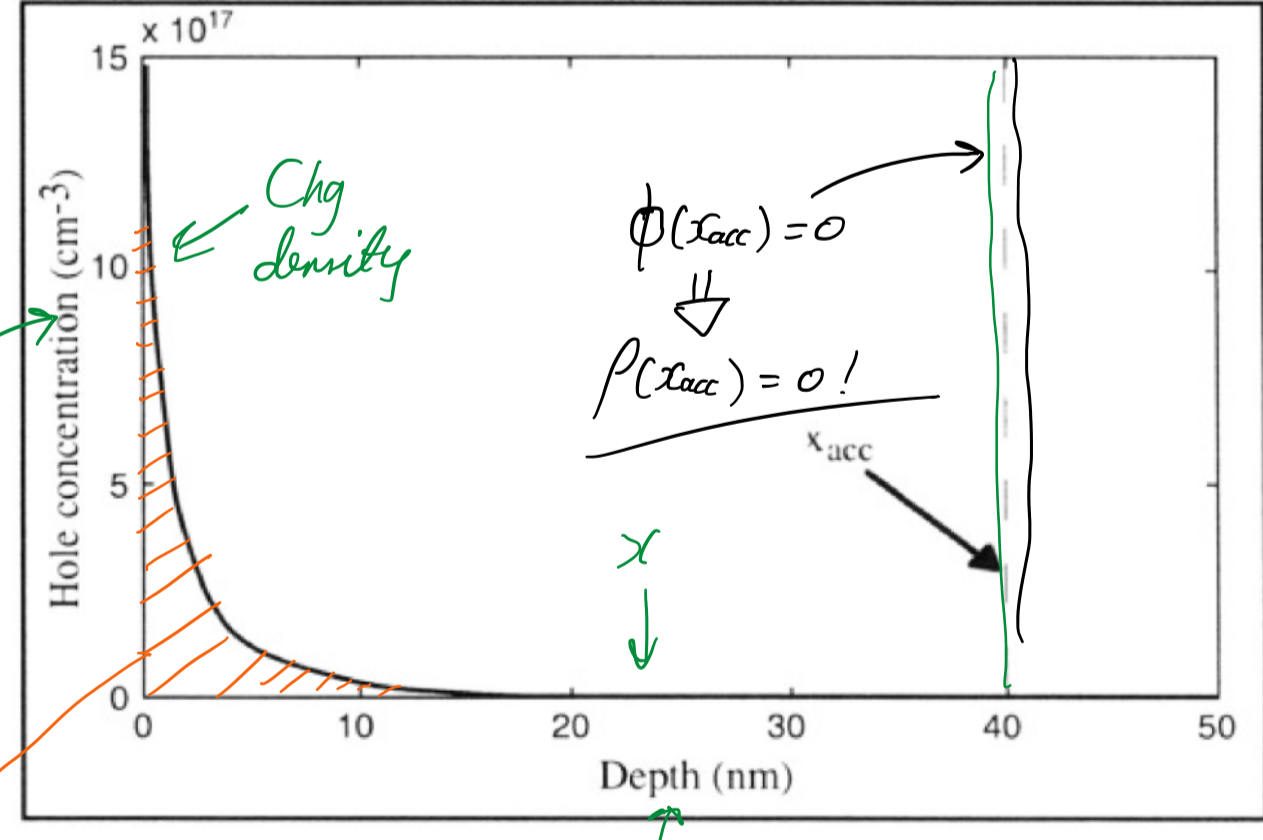
Charge Density as a function of depth given by:

$$\rho(x) = -q N_A \left[e^{\frac{-q\phi(x)}{kT}} - 1 \right]$$

Charge Density $\rho(x)$ falls off exponentially with potential

All accumulation charge is contained within x_{acc}

- We want to know total accumulation charge Q_{acc}
- We know charge density $\rho(x)$
- We can integrate $\rho(x)$ to get Q_{acc}

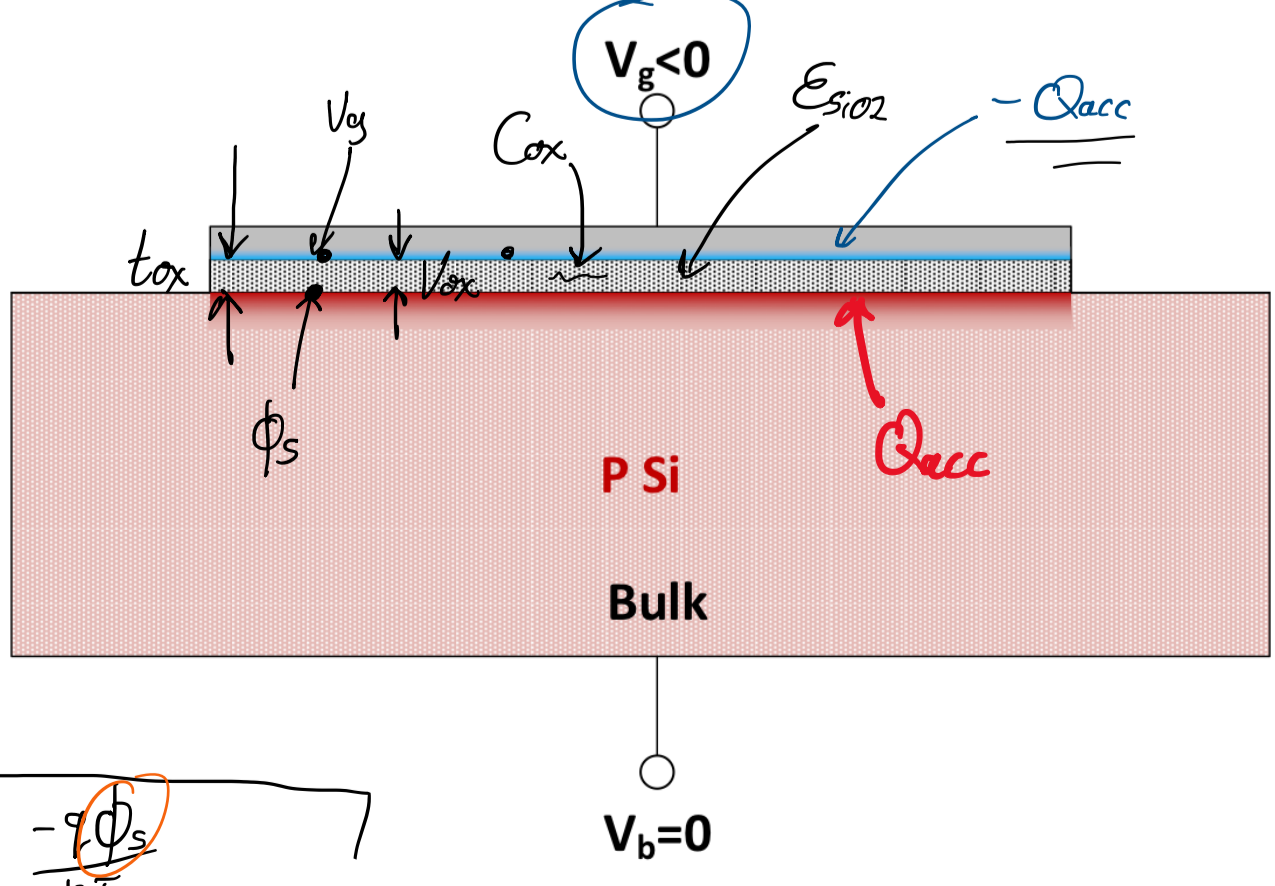


$$Q_{acc} = \int_0^{x_{acc}} \rho(x) dx = \frac{-\epsilon_{Si} \sqrt{2}}{L_D} \frac{kT}{q} \int_0^{x_{acc}} \left[e^{\frac{-q\phi(x)}{kT}} - 1 \right] dx$$

* Not Important *
understand where we get it

Linking Gate Voltage to Accumulation Charge

- We want to link V_g to Q_{acc}
- We know: $Q = CV \rightarrow V = \frac{Q}{C}$
- By KVL: $V_g = \phi_s + V_{ox}$
- $V_g = \phi_s - \frac{Q_{acc}}{C_{ox}}$



Approximate Parallel Plate Cap since $x_{acc} \rightarrow 0$

$$C_{ox} = \frac{\epsilon_{SiO2}}{t_{ox}} \quad [F/m^2]$$

$$V_g = \phi_s + \frac{\epsilon_{Si} \sqrt{2}}{L_D C_{ox}} \frac{kT}{q} \int_0^{x_{acc}} \left[e^{\frac{-q\phi(x)}{kT}} - 1 \right] dx$$

Solve for $\phi_s \rightarrow$ Use ϕ_s to find Q_{acc}